



DFW

PATENT
Customer No. 22,852
Attorney Docket No. 03180.0343

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
 Masafumi ASANO et al.)
)
 Application No.: 10/725,571) Group Art Unit: 1756
)
 Filed: December 3, 2003) Examiner: Stephen D. Rosasco
)
 For: RETICLE SET, METHOD FOR) Confirmation No.: 5144
 DESIGNING A RETICLE SET, EXPOSURE)
 MONITORING METHOD, INSPECTION METHOD)
 FOR RETICLE SET AND MANUFACTURING)
 METHOD FOR A SEMICONDUCTOR DEVICE)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

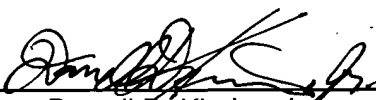
In a restriction requirement dated October 26, 2005, the Examiner required restriction under 35 U.S.C. § 121 between Group I, claims 1-10, characterized by the Examiner as being drawn to a reticle set; Group II, claims 11-17, characterized by the Examiner as being drawn to an exposure monitoring and inspecting method; and Group III, claims 18-22, characterized by the Examiner as being drawn to a method of manufacturing an integrated circuit.

Applicants provisionally elect to prosecute Group I, claims 1-10, without traverse.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: November 28, 2005

By: 
 Darrell D. Kinder, Jr.
 Reg. No. 57,460